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(12) **United States Design Patent**
Okajima et al.

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(54) **GAS NOZZLE FOR SUBSTRATE PROCESSING APPARATUS**

(71) Applicant: **KOKUSAI ELECTRIC CORPORATION**, Tokyo (JP)

(72) Inventors: **Yusaku Okajima**, Tokyo (JP); **Toru Kagaya**, Tokyo (JP); **Hiroaki Hiramatsu**, Tokyo (JP); **Shinya Ebata**, Tokyo (JP)

(73) Assignee: **KOKUSAI ELECTRIC CORPORATION**, Tokyo (JP)

(**) Term: **15 Years**

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(51) **LOC (12) Cl.** **23-01**

(52) **U.S. Cl.**
USPC **D23/213**

(58) **Field of Classification Search**
USPC D7/407, 332, 334–337, 402–405, 391, D7/392.1; D24/108, 130, 141; D23/213, D23/259, 266
CPC F23D 14/045; F23D 14/16; F23D 14/48; F23D 14/50; F23D 2203/10; F23D 2203/1012; F32D 14/10; B24B 9/007; B08B 9/00; B08B 9/021; B08B 9/032; B08B 9/027; B08B 9/02
See application file for complete search history.

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Primary Examiner — Derrick E Holland
Assistant Examiner — Andrew Kerr
(74) *Attorney, Agent, or Firm* — Fitch, Even, Tabin & Flannery LLP

(57) **CLAIM**

We claim the ornamental design for a gas nozzle for substrate processing apparatus, as shown and described.

DESCRIPTION

FIG. **1** is a front, top and left side perspective view of a gas nozzle for substrate processing apparatus showing our new design;
FIG. **2** is a front elevational view thereof;
FIG. **3** is a rear elevational view thereof;
FIG. **4** is a left side elevational view thereof;
FIG. **5** is a right side elevational view thereof;
FIG. **6** is a top plan view thereof;
FIG. **7** is a bottom plan view thereof.
FIG. **8** is a cross-sectional view take along line **8-8** in FIG. **2** thereof;
FIG. **9** is an enlarged portion view taken along line **9-9** in FIG. **2** thereof; and,
FIG. **10** is an enlarged portion view taken along line **10-10** in FIG. **8**.
The broken lines shown in the drawings represent portions of the gas nozzle for substrate processing apparatus that form no part of the claimed design.

1 Claim, 4 Drawing Sheets

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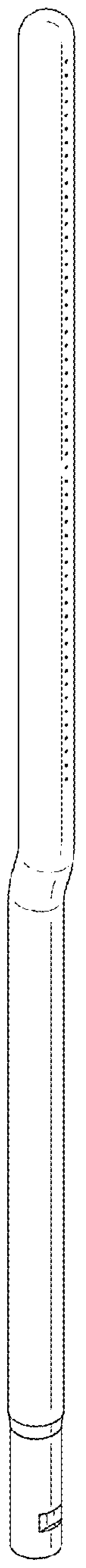

FIG. 1

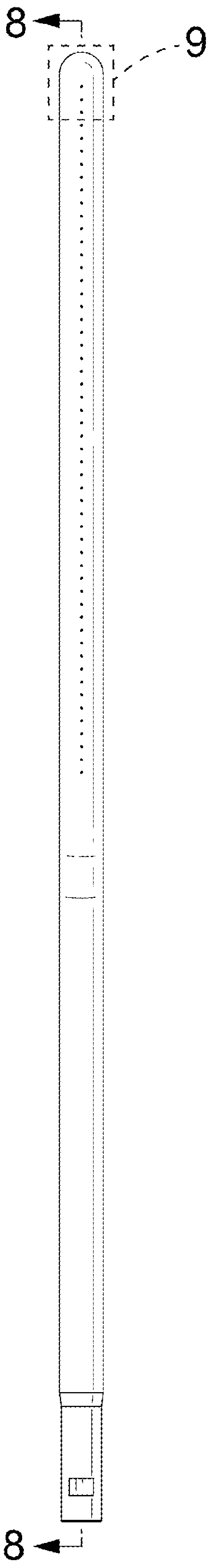

FIG. 2

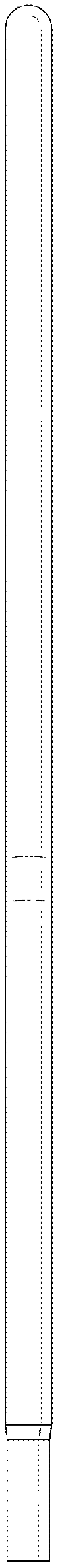

FIG. 3

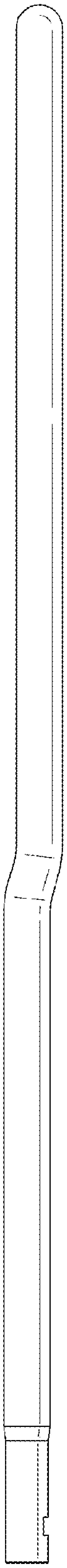

FIG. 4

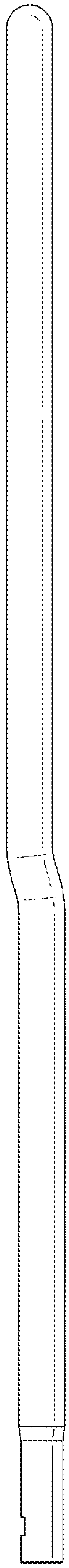

FIG. 5

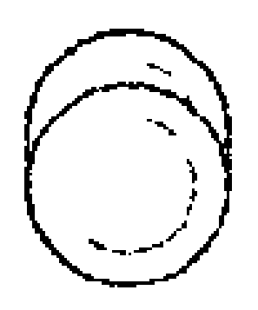

FIG. 6

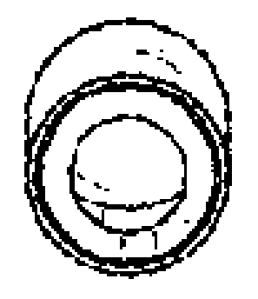

FIG. 7

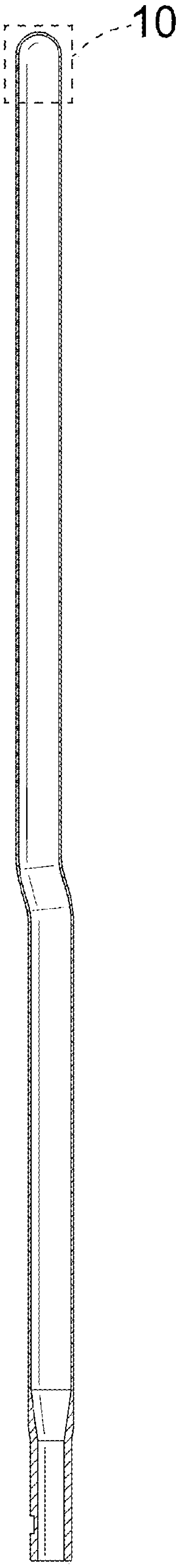

FIG. 8

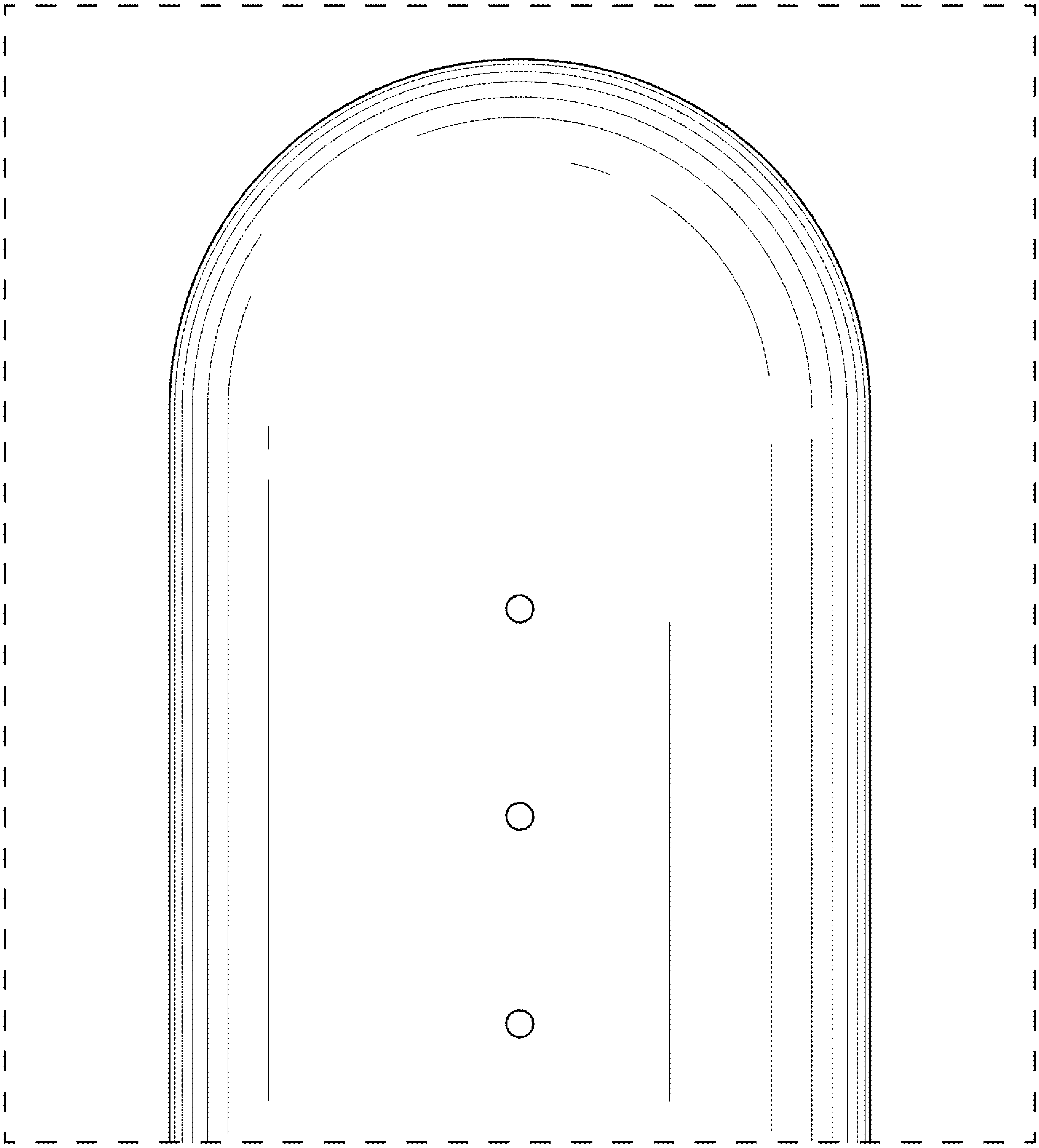

FIG. 9

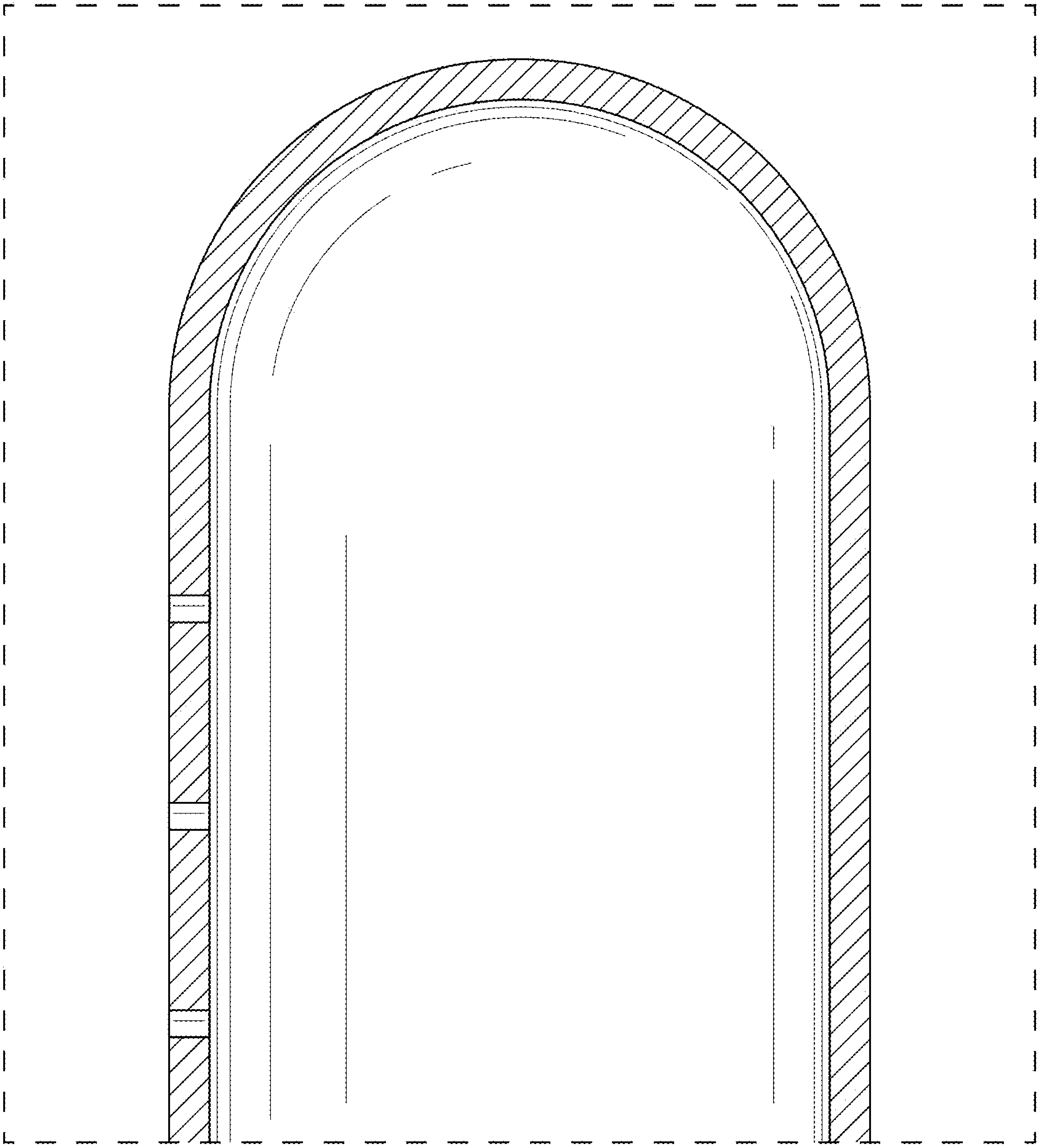

FIG. 10